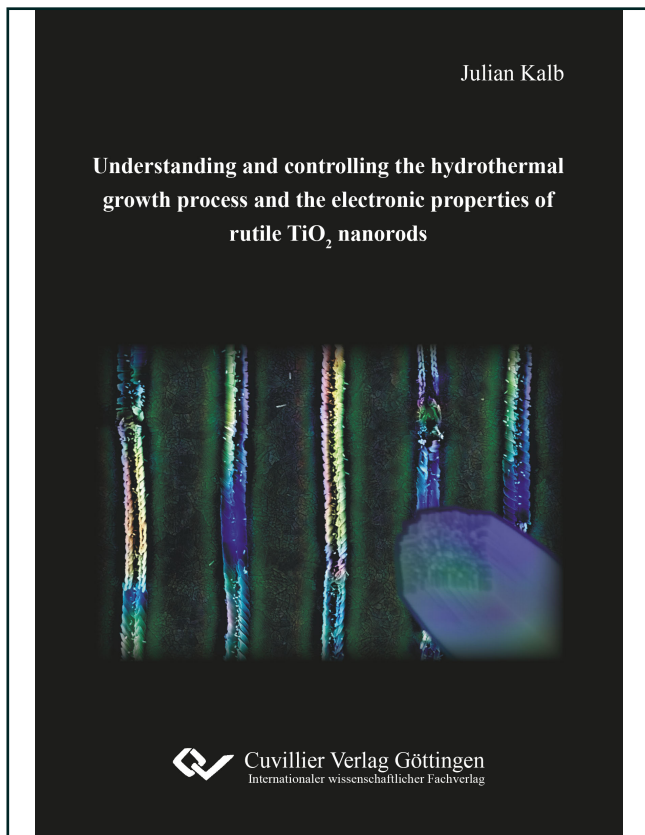




Julian Kalb (Autor)

Understanding and controlling the hydrothermal growth process and the electronic properties of rutile TiO₂ nanorods



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